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Figures 5-7, as amended, includes change of the reference number from “254” to –360-- due to typographical error, which is described in the specification at least at page 8, lines 15-18, “A drive arm actuator 360 located below the bottom 208 and is connected to the first pivot pin 356 to impart rotation to the first drive arm 354”, at page 8, lines 23-26, “A drive member 374, such as a belt shown in phantom form in Figure 3, couples the second drive arm 354' to the drive arm actuator 360 assuring symmetrical extension of the linkage 352”, and at page 9, lines 18-21, “When the drive arm actuator 360 (shown in Figure 2) imparts simultaneous counterclockwise and clockwise rotation to the first drive arm 354 and second drive arm 354', respectively, the linkage 352 and blade 262 are moved along the transfer plane B”.

Figure 8, as amended, includes change of the reference numbers from “206” to –204--, and from “426” to –424-- due to typographical error, which are described in the specification at least at page 6, lines 10-11, page 7, lines 29-30, page 11, lines 14-28, “A wafer support 424 is provided to support a wafer thereon below the transfer plane of internal robot 204”, and page 15, lines 8-17.

Figure 10A-10B, as amended, includes the omitted reference number “254” at the indicated position, which is described in the specification at least at page 7, lines 15-16, “A pneumatic cylinder 254 actuates a sealing door 256 to engage a seating surface 258 on the chamber wall 210”. In addition, Figure 10A-10B, as amended, includes change of the reference numbers from “434” to –424-- due to typographical error, which are described in the specification at least at page 11, lines 14-28, “A wafer support 424 is provided to support a wafer thereon below the transfer plane of internal robot 204”, and page 15, lines 8-17.

Figure 10F-10G, and 10O, as amended, includes the omitted reference symbol “B” due to typographical error. The symbol “B” indicates a transfer plane B at the indicated position, which is described in the specification at least at page 7, lines 11-12, and lines 29-30, page 8, lines 13-15 and lines 27-29, page 9, lines 18-21, page 10, lines 3-5, page 14, lines 16-19, “The wafer is deposited onto the blade 262 by lowering the first pair of lift forks 420 below the transfer plane B as shown in Figure 10f. The lift elements 432 of the first pair of lift forks 420 are rotated 90 degrees and returned to a

position above the transfer plane B as shown in Figure 10g", and page 15, lines 3-18.

Figure 13, as amended, includes the change one of the reference numbers "704" to -705— due to typographical error for duplicated reference number "70". Thus, Figure 13, as amended, include one reference number "704" to indicate the mini-environment, which is described in the specification at least at page 18, lines 3-13; and one reference number "705" to indicate the track 705 at the indicated position, which is described in the amended specification at least at page 17, lines 26-30, and page 18, line 1.

Applicants respectfully submit that the proposed amendments conform the drawings to the written description of the invention and do not introduce new matter. Approval of the amendments is respectfully requested.

Respectfully submitted,



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